



Electroplating Through Holes with Different Geometry -- A Novel and High Productivity Process for Through Hole Fill Plating

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TOPIC

- Background
- Copper Through Hole Fill Capability
- Formulation
- Effects of hole geometry
- Effects of process parameters
- Substrate and metallization effects
- Pilot scale cycling test
- Physical properties and reliability
- Summary



Through-hole Fill Build-up Process



- Excellent copper to copper adhesion, providing improved reliability
- No CTE mismatch within filled via structure
- Increased productivity and reduced costs



Copper Through Hole Fill Performance Metrics



- Dimple Depth = H_1
- Aspect Ratio = H_2/Dia
- Void Area = 0.5A x 0.5B x π
- Hole Area = $H_2 \times Dia$
- % Void Area = Void Area/Hole Area x 100%



Product Capability

MICROFILL TM THF Bath Key Capabilities:

- Substrate Thickness :
- Hole Diameter •
- Hole Geometry :
- Rectification
- Current Density
- Dimple Depth $\leq 10 \ \mu m$
- Plated Copper Thickness
- Temperature
- Substrate Metallization :
- Compatible with Insoluble Anodes
- Panel and Pattern Plate Compatible
- CVS Analysis for all Organic Components

100 μm – 200 μm 75 μm – 100 μm Mechanical and laser drilled Direct Current : $10 - 25 \text{ A/ft}^2 (1 - 2.5 \text{ASD})$

$$\leq$$
 25 μm

Electroless Copper



Optimized Formulation

Single Step DC Plating – MICROFILLTM THF Bath

Operating Parameters	Range	Recommended
Copper Sulfate Pentahydrate	220 - 230 g/L	225 g/L
Sulfuric Acid	35 - 45 g/L	40 g/L
Chloride	40 - 60 mg/L	50 mg/L
MICROFILL TM THF Brightener Solution	5.0 - 6.5 mL/L	5.75 mL/L
MICROFILL TM THF Carrier Solution	10 - 15 mL/L	12.5 mL/L
MICROFILL TM THF Leveler Solution	2.25 – 3.25 mL/L	2.75 mL/L)



Impact of Through Hole Geometry

MICROFILLTM THF Bath is Capable of Filling Through Hole (TH) with Range of Different Shapes :



Effect of Jet Impingement Flow Rate

Excessive solution flow increases dimple depth



Effect of Current Density



- \bullet Process performs very well at high current densities, dimple $< 10 \, \mu m$
- \bullet Low current density improves TH void performance with 200 μm thick panels
- The small loss of fill performance due to increasing current density is greater at higher substrate thicknesses







Effect of Hole Diameter & Copper Thickness on Fill



The amount of plated copper to achieve a completely filled TH is dependent on hole size. Less plated copper is required to fill smaller diameter holes than larger diameter holes
Depending on geometry size, MICROFILLTM THF bath is capable of filling through holes with copper thickness less than 20 µm.



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Impact of Substrate Metallization on Fill

MDTH μ 100μm x100μm Electroless thickness: 0.5-1.25 μm

MDTH 100 μm x 100μm Electroless thickness: 0.2-0.5 μm

DSLTH 100 µm x 100µm Electroless thickness: 0.2-0.5 µm

OSLTH 100 μm x 100μm Flash copper thickness: 1.0-4.0 μm





- THF performance is similar whether used with medium or low build electroless
- The quality and thickness of electroless copper affects THF performance
- THF performance decreases with decreasing electroless copper coverage
- The impact of poor coverage on THF performance is greater for low build electroless
- THF can be used also with electrolytic copper flashed substrates

Fill Performance as a Function of Bath Age



Consistent through hole fill performance with low dimple

Bath Age	10 A/ft ²	15 A/ft ²	20 A/ft ²	Bath Age	100 µm dia x 100 µm thick	100 µm dia x 200 µm thick
0 Ah/L				0 Ah/L		
100 Ah/L				150 Ah/L		

Through Hole Fill Deposit Physical Properties



Tensile Strength and Elongation measured per IPC-TM 650 2.4.18.1



Through Hole Fill Reliability

Thermal Stress IPC-TM 650 2.6.8

	THF Bath Age			$CD = 15 \Lambda SE$	
	0 Ah/L	50 Ah/L	100 Ah/L	150 Ah/L	CD = IJ ASF
Hole Size	Nur	Number of cracks / number of holes			Cu = 25 um
100 μm dia x 100 μm thick	0/120	0/120	0/120	0/120	
100 μm dia x 200 μm thick	0/120	0/120	0/120	0/120	

CD (ASF) / Panel Thickness	Defects/ Total Holes Inspected	Cross Section
25 / 100 µm	0 / 220	
25 / 200 µm	0 / 220	

Excellent deposit performance throughout the range of bath age and current densities evaluated



Blind Microvia Fill Performance

 MICROFILLTM THF bath can also be utilized for the metallization of Blind Micro Via (BMV) with surface copper thicknesses of less than 15 μm. This system may be utilized for BMV plating for Every Layer Interconnect (ELIC) HDI and IC substrate applications.





Conclusion

- Product is commercialized world wide. DC through hole fill process developed for HDI and IC package substrate.
- Consistent through hole fill performance with low dimple depth $< 10 \ \mu m$
- Excellent fill performance, with mechanically drilled holes, and laser drilled holes
- High filling performance on substrates metallized with different thicknesses of electroless copper
- Excellent fill performance with dimple $< 10 \,\mu m$ at range of CD up to 25 ASF
- Good deposit physical properties. Solder Float results showed no cracks.
- Depending on hole geometry, the MICROFILLTM THF Bath demonstrates superb filling performance with surface copper thickness between15µm and 25µm.
- Highly leveled surface free of nodules and pits. All bath additive components can be monitored by CVS
- Excellent blind microvia fill performance.





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